

**METHOD OF FORMING A PHOTO SENSOR ON SEMICONDUCTOR
WAFER WITH OVERLAPPED REGION**

Appl. No. : 10/065,296 Confirmation No. 5720
Applicant : Liang-Hua Lin,
Anchor Chen
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TC/A.U. : 2813
Examiner : Kielin, Erik J
Docket No. : NAUP0477USA1
Customer : 27765
No.

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Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

AMENDMENT

Sir:

- 5 In response to the final Office action of 08/25/2004, a request for continued examination is submitted and amendments to the above-identified application are as follows:

Amendments to the Specification begin on page 3 of this paper.

- Amendments to the Claims** are reflected in the listing of claims which
10 begins on page 4 of this paper.

Amendments to the Drawings begin on page 8 of this paper and include

both an attached replacement sheet and an annotated sheet showing changes.

Remarks/Arguments begin on page 9 of this paper.

An Appendix including amended drawing figures is attached following
5 page 21 of this paper.